

AMENDMENTS TO THE CLAIMS

This listing of claims replaces all prior versions, and listings, of claims in the application:

1. (previously presented) A device comprising a drain, a gate, a channel, and a source, having sufficiently symmetric paths from source to drain for electrons and for holes such that the device acts like a NMOS when drain to source (VDS) and gate to source (VGS) voltages are positive, and acts like a PMOS when drain to source (VDS) and gate to source (VGS) voltages are negative, and wherein a source to channel barrier height can be modulated by a field-effect, and a channel to drain barrier height is not affected by gate bias.
2. (original) The device of claim 1 wherein the device is a metal insulator semiconductor field effect transistor (MISFET) comprising source, drain, and gate regions wherein the electrostatic potential in each of the source, drain, and gate regions is symmetric for electrons and holes, with the source to channel interface being different from the channel to drain interface.
3. (canceled)
4. (previously presented) The MISFET of claim 2 comprising:
a source layer being made with a material having a source band-gap (EG2) and a source mid-gap value (EGM2), said source layer having a source Fermi-Level (EF2);
a drain layer having a drain Fermi-Level (EF4);
the channel comprising a channel layer between the source layer and the drain layer, said channel layer being made with a material having a channel band-gap (EG3) and a channel mid-gap value (EGM3), said channel layer having a channel Fermi-Level (EF3);
a source contact layer connected to the source layer opposite the channel layer, said source contact layer having a source contact Fermi-Level (EF1); and
a gate electrode having a gate electrode Fermi-Level (EF6)
wherein:
said source band-gap (EG2) is substantially narrower than said channel band-gap (EG3);

said source contact Fermi-Level (EF1), said source Fermi-Level (EF2), said channel Fermi-Level (EF3), said drain Fermi-Level (EF4) and said gate electrode Fermi-Level (EF6) are equal to said source mid-gap value (EGM2) and said channel mid-gap value (EGM3), within a predetermined tolerance value, when no voltage is applied to the device such that all electrodes are at the same potential.

5. (original) The MISFET of claim 4, wherein the first band-gap is at least 9 to 10 times narrower than said second band-gap.
6. (original) The MISFET of claim 5, wherein the first band-gap (EG2) is in the order of 0.1 to 0.12 electron-volts (eV) and the second band-gap (EG3) is in the order of 1.0 to 1.2 electron-volts (eV).
7. (previously presented) The MISFET of any one of claims 4, 5, and 6, wherein the predetermined tolerance value is lower than 10%, respectively, preferably lower than 5% of the channel band-gap.
8. (previously presented) The MISFET of claim 4 comprising:
 - a epitaxial titanium nitride (TiN) source contact;
 - a source layer coupled to the source contact, the source layer comprising $\text{Si}_{1-x-y}\text{Ge}_x\text{Cy}$ alloys, or superlattices of alternating $\text{Si}_{1-x}\text{Ge}_x$ and Si_{1-y}Cy ;
 - an un-doped silicon (Si) channel layer coupled to the source layer;
 - an epitaxial titanium nitride (TiN) drain layer coupled to the channel layer;
 - a titanium nitride (TiN) gate electrode coupled to at least one of the source layer, un-doped silicon channel layer, and drain layer via an insulator.
9. (original) The MISFET of claim 1 comprising a channel, the channel consisting essentially of Ge or strained-layer short period superlattices of GeSiSn/Ge , or GeSi/SeSn or SiSn/Ge .
10. (original) The MISFET of claim 1 wherein the source consists essentially of $\text{Ge}_{1-\text{x}}\text{Sn}_{\text{x}}$ strained-layer short period superlattices, strained to 111 Ge substrates.

11. (original) The MISFET of claim 1 wherein the source comprises a material having a band-gap around 0.1eV.
12. (original) The MISFET of claim 1 comprising a source contact that is a conductor whose Fermi-level is aligned with the mid-gap point of the source and channel materials.
13. (original) The MISFET of claim 1 wherein the drain comprises a material that is a conductor whose Fermi-level is aligned with the mid-gap point of the source and channel materials.
14. (original) The MISFET of claim 1 comprising a gate electrode, the gate electrode comprising a material that is a conductor whose Fermi-level is aligned with the mid-gap point of the source and channel materials.
15. (previously presented) The MISFET of claim 1 wherein the gate insulator comprises at least one of: GeON (germanium oxynitride), ZrO₂ and, BaTiO.
- 16-18. (canceled)
19. (previously presented) A device comprising a drain, a source, channel, gate(s), and source, gate, and drain electrodes, wherein:
 - the source is coupled to the channel at a source to channel interface, wherein a source to channel barrier height can be modulated by a field-effect, and a channel to drain barrier height is not affected by gate bias;
 - the channel is coupled to the drain at a channel to drain interface;
 - the source to channel interface differs from the channel to drain interface; and
 - the electrostatic potential for electrons and holes is symmetric with respect to the mid-gap level, along a cut from source to drain, on a plane near an interface with a gate and on a plane far from an interface with a gate, when zero voltage is applied to the source, drain, and gate electrodes.
20. (previously presented) A device comprising a drain, a source, channel, and gate(s) wherein:

the source is coupled to a channel at a source to channel interface, wherein a source to channel barrier height can be modulated by a field-effect, and a channel to drain barrier height is not affected by gate bias;

the channel is coupled to the drain at a channel to drain interface;

the source to channel interface differs from the channel to drain interface; and

any cut along a line perpendicular to the plane of a gate, through the source layers, or through the channel layers, or the drain layers, exhibits a flat band condition along that line.

21. (previously presented) The MISFET of claim 1 comprising a source contact and a gate electrode wherein the same materials are used for the source contact, drain, and gate electrode.